



MiniMEMS

High-Reliability, High-Power & High-Speed RF Tuning Applications
based on **Miniaturised MEMS** Switched Capacitors

A. Ziaei, S. Demoustier

EURIPIDES EoI – October 10th, 2008 – Berlin

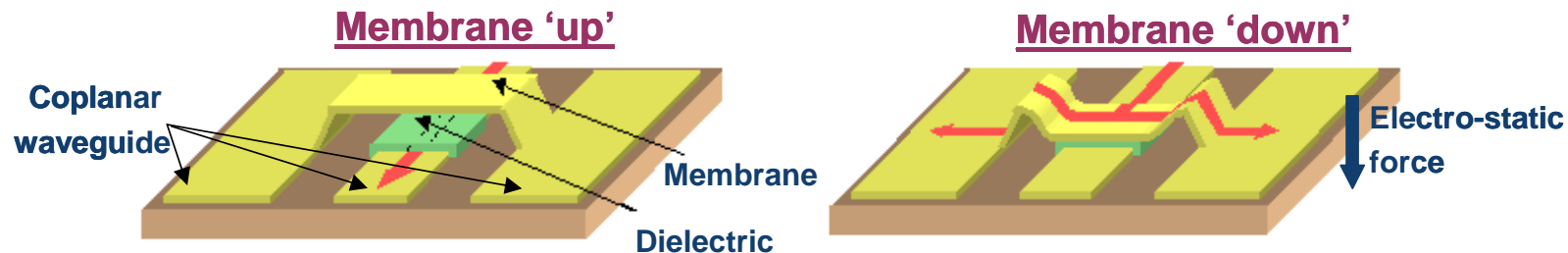


Reasons of enthusiasm for RF-MEMS

- ▶ High RF performances (wideband, low loss, high isolation, high linearity)
- ▶ Very low power consumption

Two capacitive approaches

- ▶ Capacitive switch: $C_r=30-200 \Rightarrow$ for routing purpose
- ▶ Switched capacitor: $C_r=2-10 \Rightarrow$ for tunable/reconfigurable functions



Main current issue: long-term reliability (& high-power handling)

- ▶ Dielectric charging
- ▶ Temperature sensitivity of the fixed-fixed beam

And low switching time

- ▶ $> 1 \mu s$ (to be compared to solid-state techno. $< 0.1 \mu s$)



New device of MEMS switched capacitors for RF tuning applications

- ▶ Mitigating dielectric charging effect and temperature sensitivity
- ▶ Allowing switching time in the order of 0.1 μ s

Based on miniaturisation of standard capacitive MEMS switch

- ▶ Enhancing mechanical properties
- ▶ Leading to high-reliability, high-power and high-speed capabilities

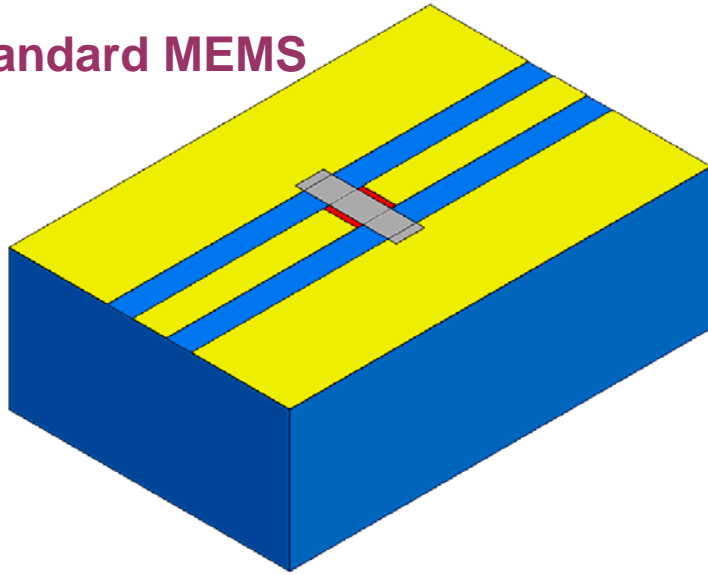
Purpose of MiniMEMS

- ▶ Development of technological steps and methodologies to achieve fabrication of miniaturised switched capacitors
- ▶ Integration into elementary RF functions:
 - ▶ Tunable filters for adaptive receivers (X-Band)
 - ▶ 3-bit phase shifters for reflect array antennae (X-Band)
- ▶ Fabrication of demonstrators showing the benefits of the technology
 - ▶ Adaptive receiver for ATM applications
 - ▶ Partial reflect array for weather and wake vortex detection radars

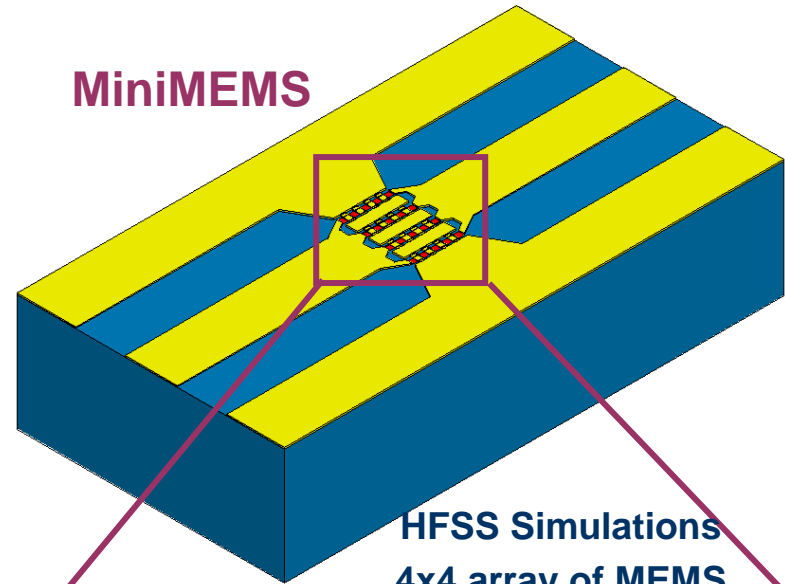
MiniMEMS Project Innovation



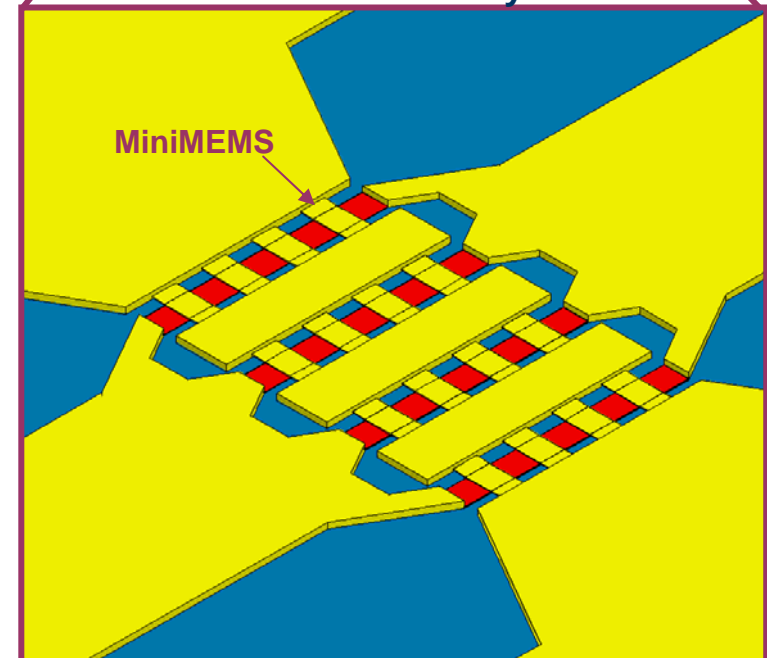
Standard MEMS



MiniMEMS



HFSS Simulations
4x4 array of MEMS



| | Standard MEMS | MiniMEMS |
|-------------------|-------------------------|-----------------------|
| Beam size | 250x100 μm^2 | 20x10 μm^2 |
| Gap | 2 μm | 0.25 μm |
| Capacitance ratio | 30-150 | 3-30 |
| Switching time | > 1 μs | 200 ns |
| Reliability | < 10^{10} | > 10^{11} |
| Power handling | < 5 W | 5 W |

Enhanced mechanical properties thanks to the miniaturisation

- ▶ Spring constant \nearrow but gap $\searrow \Rightarrow$ pull-down voltage \approx constant (30 V typ.)
- ▶ Gap $\searrow \Rightarrow$ capacitance ration $C_r \searrow$ (3 typ.)
 - ▶ Use of ZrO_2 or PZT instead of $Si_3N_4 \Rightarrow$ aimed $C_r \nearrow$ by a factor 10
- ▶ Resonant frequency $\nearrow \Rightarrow$ switching time \searrow
- ▶ Critical stress \nearrow and residual stress \searrow by 70%
 \Rightarrow much more stable vs temperature variations (in terms of spring constant, V_p and capacitance)
 \Rightarrow can be packaged under higher T° conditions
- ▶ Pulling pressure $\nearrow \Rightarrow$ withstand higher charge density before failing in down state position \Rightarrow dielectric charging effect \searrow

Array of MiniMEMS for 6-100GHz applications

- ▶ Capacitance value of 1 MiniMEMS too small (3-15fF) for RF applications
 - ▶ 6x6 array for X-Band
 - ▶ 3x3 array for Ka- & Q-Band
 - ▶ 4x4 array for Ku- & K-Band
 - ▶ 2x2 array for > 50 GHz

Risk evaluation

| Nature of risk | Risk | Contingency Plan |
|----------------|--|--|
| Technical | At reduced scales, the planarity / roughness of the beam is critical | Use of chemical-mechanical planarisation techniques |
| Technical | Capacitance values not high enough to meet RF application requirements | Several dielectric layers will be used: Si ₃ N ₄ , ZrO ₂ , PZT Several devices can be built in parallel |
| Technical | Reliability not met due to packaging issues | 3 types of packaging techniques will be studied in parallel |
| Market | Components and products developed by non European companies (USA are very active in this domain) with impact on European sales | Design methodologies and processes developed in MiniMEMS will allow industrialisation transfer to foundry (technology transfer to UMS at the end of the project) |

Exploitation potential

| Road Map MEMS for Reflect Array and ATM | | | | |
|---|----------------|----------------|------|--------------------------|
| Application | Frequency Band | MEMS operation | Year | Market in number of MEMS |
| Data Link Satellite-Aircraft communications | X | 5000 h | 2012 | 10 ⁷ |
| Weather and wake vortex Radar | X | 1000 h | 2012 | 3.10 ⁶ |

Project duration: 36 months

- ▶ Phase 1: Component and system specifications (6 months)
- ▶ Phase 2: Design, fab. and test of packaged switched capacitors components (15 months)
- ▶ Phase 3: Design, fab. and test of tunable filters and phase shifters (9 months)
- ▶ Phase 4: Partial reflect array and adaptive receiver demonstration (9 months)
- ▶ Phase 5: Exploitation activities
- ▶ Phase 6: Project Management